

Micro-Nano Sensors & Actuators for Use in Extreme Environments

Bruce Tuttle, Geoff Brennecka, Chris Applett, Joe Henfling,
Chad Parish and Paul Galambos

Sandia National Laboratories

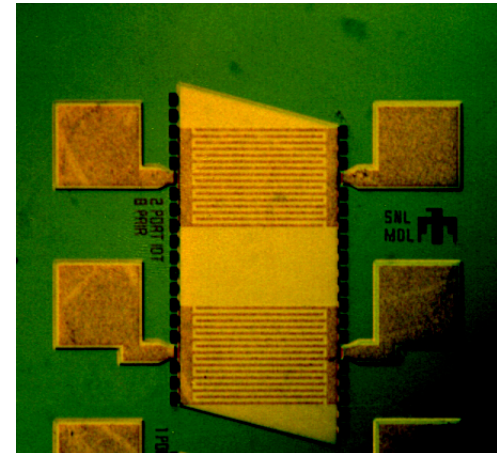
John Ekerdt University of Texas at Austin,

Paul Nealey, University of Wisconsin

Jacob Jones, University of Florida



NINE Workshop
Marriott Hotel
Albuquerque, NM
July 29, 2008



Bulk Acoustic Surface Wave
Piezoelectric Sensor



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Multilayer Piezoelectric Fuel Injector

Extreme Environment Sensors and Actuators Needed For Many Applications



**Unattended Ground
Sensors**



**Down Hole Well
Drilling**



**Process Control,
Integrated Electronics
And
Bio – Medical**

Nano-Micro Materials Advances Required to Improve Sensor Technology



Example: Pressure Measurement Improvements Needed for Down Hole Well Drilling

There are Many Other Sensor Applications that NINE Teams Can Impact

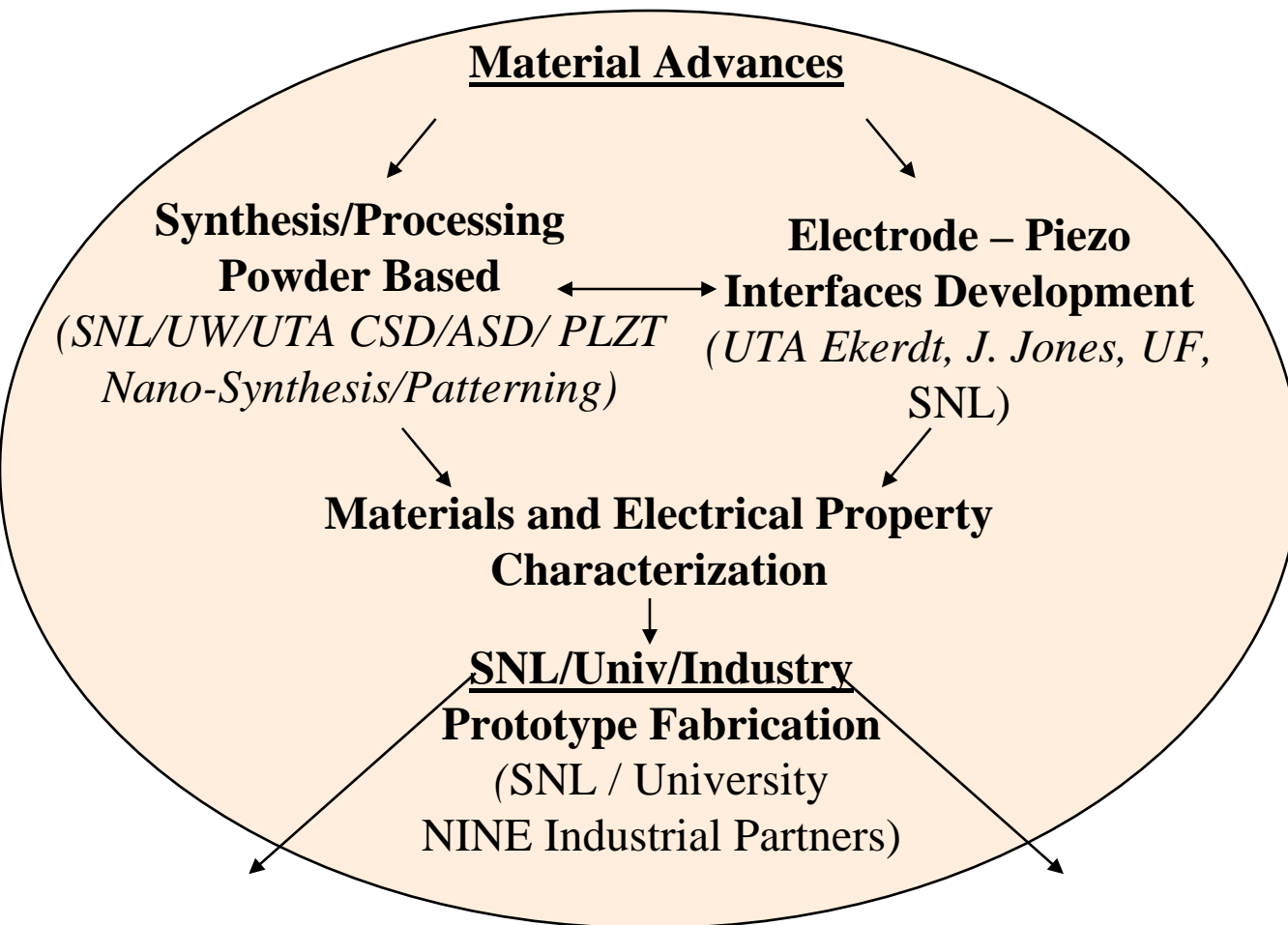
**Improved Sensors Will Save Millions of Dollars
for U.S. Down Hole Well Drilling Industry**

Improvements Needed

- Reliably measure small changes in dynamic pressure
 - High resolution
 - Smaller packages
 - Higher Temperature (HT) Performance
- Highly Stable Pressure Sensors
 - Minimal drift at high temperatures $> 150^{\circ}\text{C}$
 - Replace strain gauges

Solution: Form NINE Team of Industry, SNL, UTA, Univ of Wisconsin, U of Florida with Materials, Commercial Innovations and Prototype device capabilities to develop microstructure and element patterning at the nanoscale level that will enable next generation HT piezoelectric sensors with improved sensitivity and stability (drift)

NINE Micro-Nano Sensor Project Will Enable New Well Drill Capabilities Via Materials Advances



Project Manager:
J. Voigt SNL DM

Principal Investigators:
G. Brennecka,
B. Tuttle SNL Staff

Team Members:
J. Ekerdt (UTA)
P. Nealey (UW)
J. Jones (UF)
J.Henfling, P.Galambos
B.Hernandez, D.Moore
C. Parish (SNL)
Industry

Nanomaterials/Analyses/ Patterning

P. Nealey, UW
J. Ekerdt, UTA
J. Jones, UF; C. Parish SNL

Prototype Fabrication

G. Brennecka, B. Tuttle
P. Galambos (Adv. MEMS)
J. Henfling (Geo Therm Res)

Sandia Has Down Hole Expertise Via Energy Research and Systems Analysis

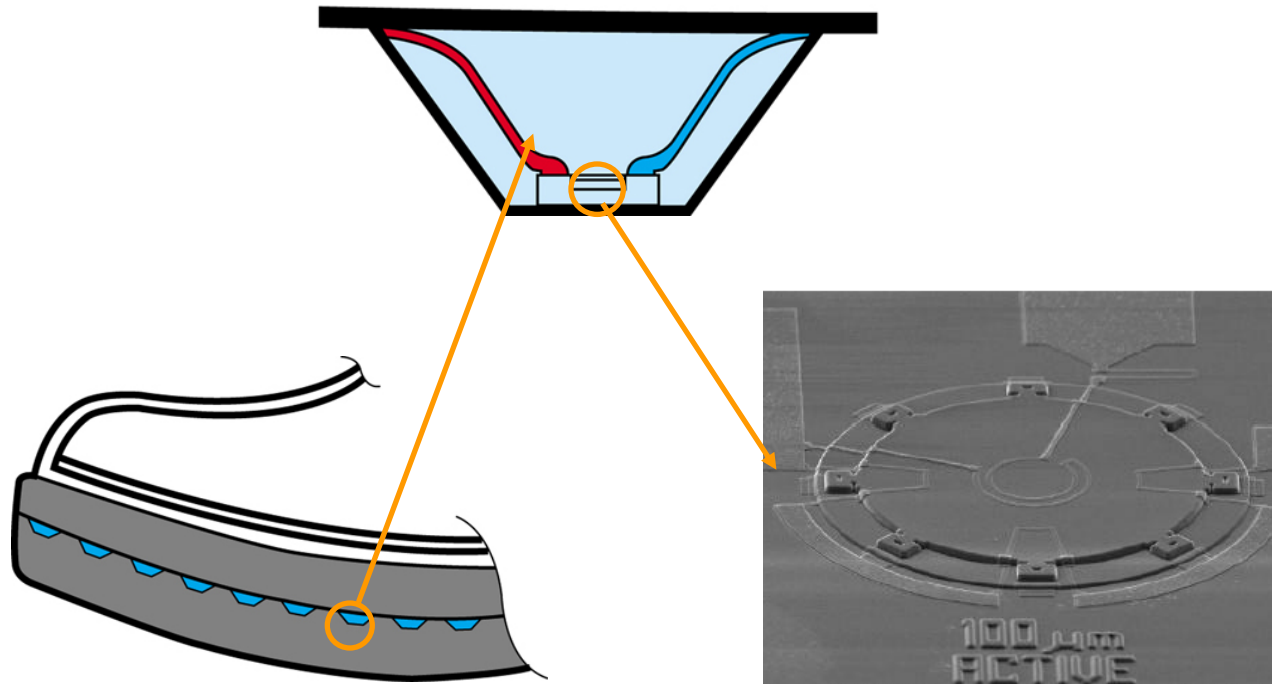
- Down Hole Life Time Studies
SOI microelectronics,
Capacitors, Pressure Sensors
- TPS Dewared Memory Tool
- Fluid Sampler
- DWD POC and HT Drilling Tool
- Dewarless PTL monitoring tools
(USGS and NETL)
- 300 °C Analog PT Well
Monitoring Tools



200°C SNL Tests of SOI Microelectronics

Microelectronic Sensors Developed to Monitor Soldiers for DARPA

- Advanced MEMS Pressure Sensor Design and Fabrication Capability (Paul Galambos)

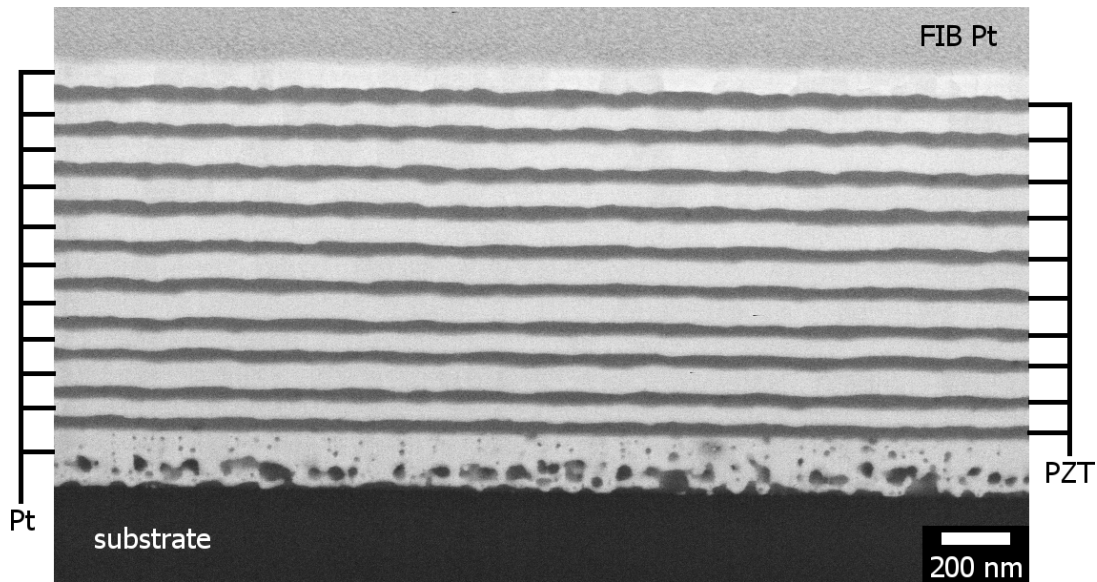


Provides Load History – Monitors soldier activities (DARPA)
Have also Invented a MEMS array Normal Stress Sensor for
Monitoring Penetrator Loading

System Needs / Initial Prototypes Drives Materials Advances

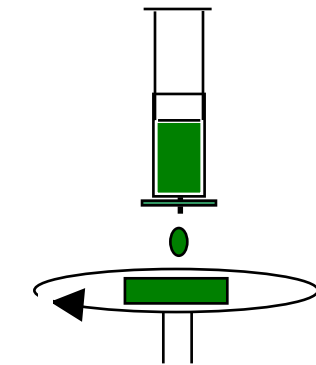
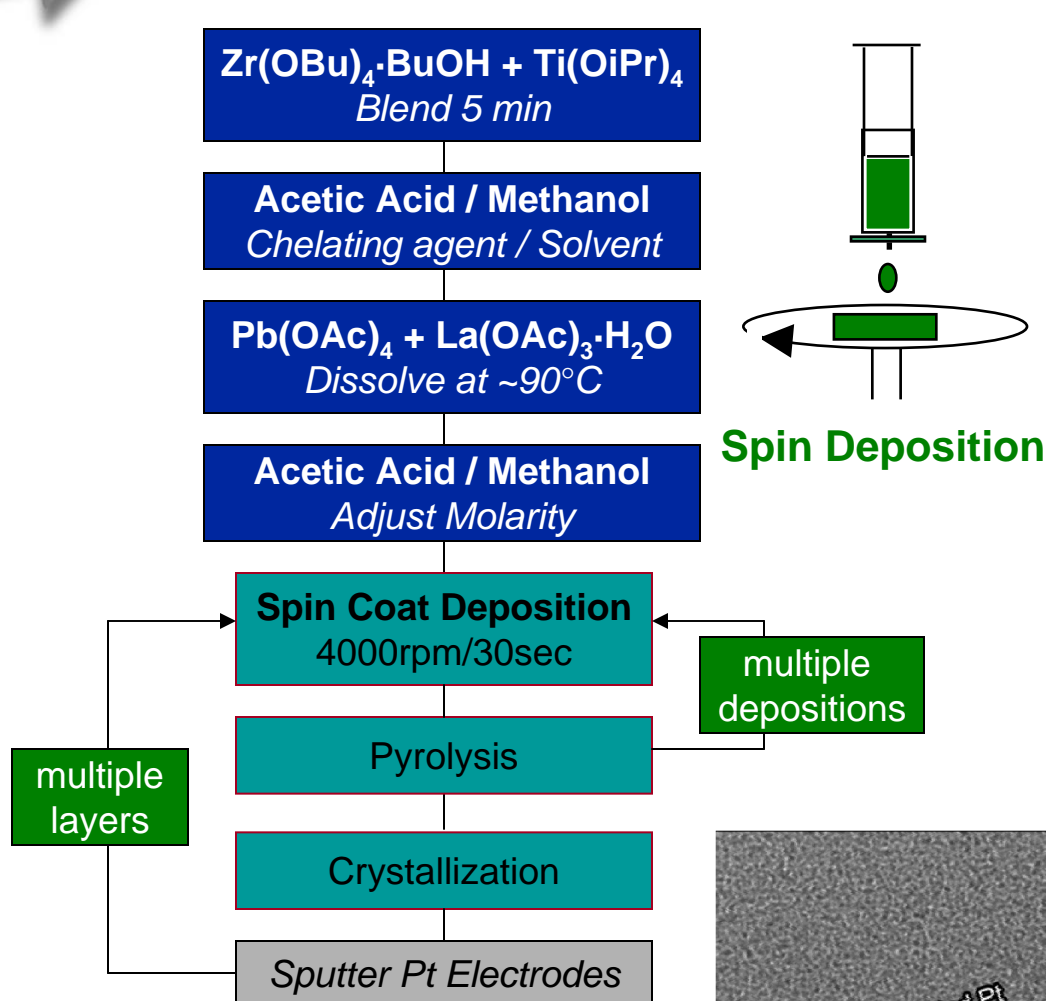
- MEMs Devices / PZT based piezoelectrics
 - FPW Devices, Motion Detectors
 - Nanopowder 3D Actuator Elements
 - Bio-Lab on a Chip Applications
 - Ultrathin Film PLZT Multilayer Capacitors
- Metal Contacts
- Non Pb Containing Materials Development

SNL Has Highest Known Large Operating Temperature Range Areal Capacitor Technology

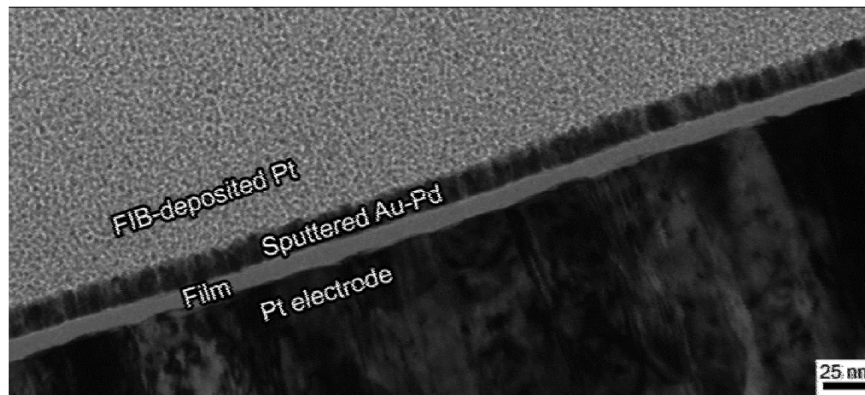
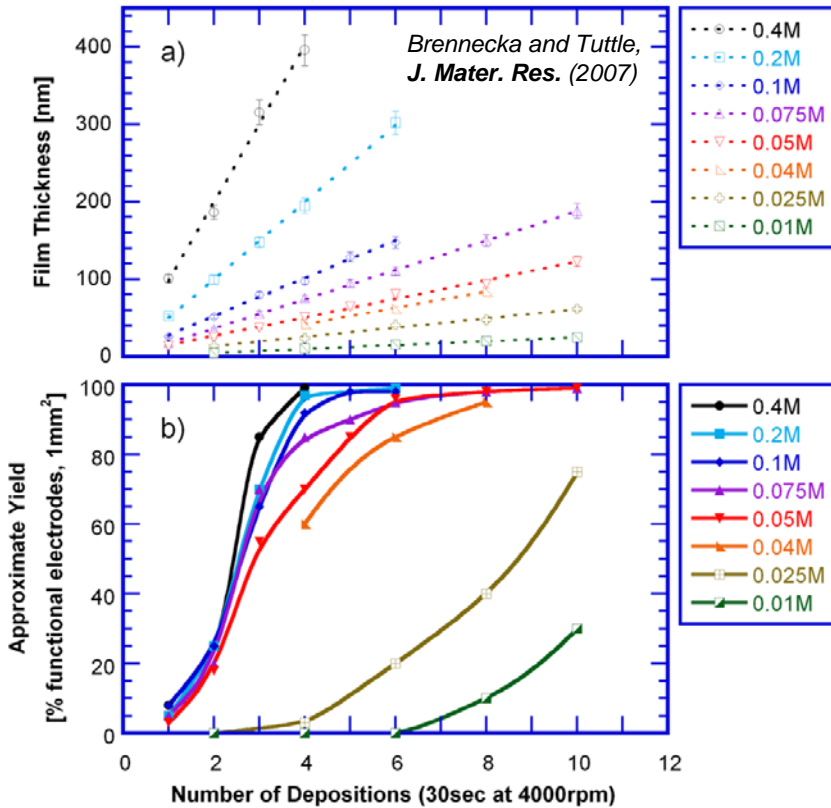


10 layer, 50 nm thick PLZT Layers
 $1 \mu\text{F}/\text{mm}^2$

SNL IMO-based Solution Route



Spin Deposition



Continuous single-phase films as thin as 9nm

Sigman, Brenneka, Clem and Tuttle.,
J. Am. Ceram. Soc. (2008)

B.A. Tuttle and R.W. Schwartz;
MRS Bulletin (1996)

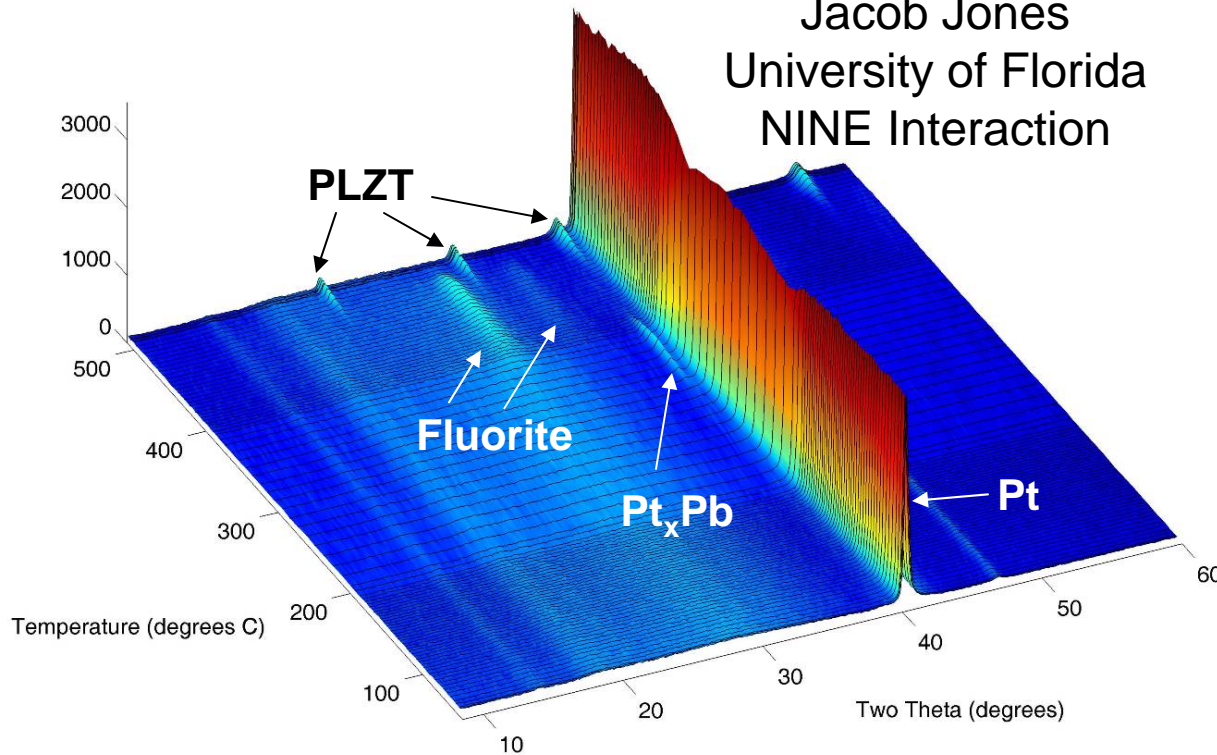
G. Yi and M. Sayer;
J. Appl. Phys. (1988)



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in-situ & *ex-situ* Studies of Phase/Interface Development

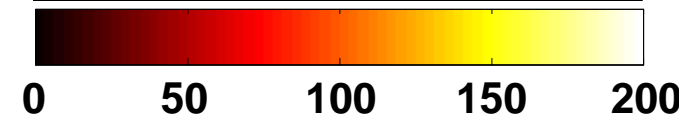
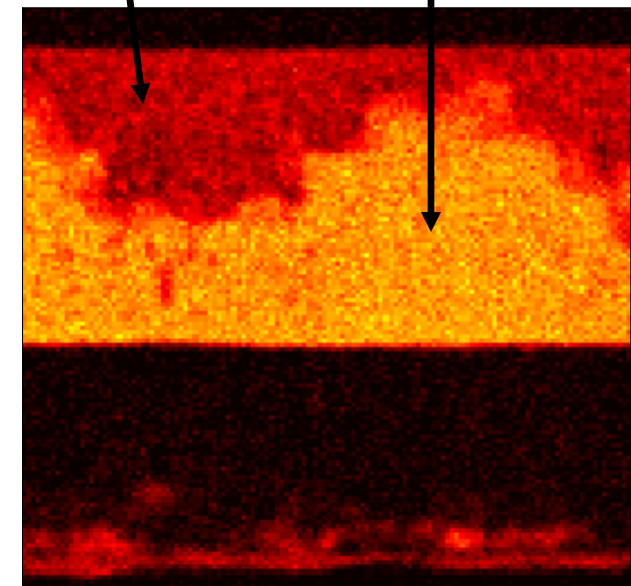
Jacob Jones
University of Florida
NINE Interaction



- *in-situ* hot-stage XRD reveals presence and effects of transient phases
- *ex-situ* quantitative chemical spectrum imaging in TEM relates chemistry to phase/interface information from XRD with high spatial resolution

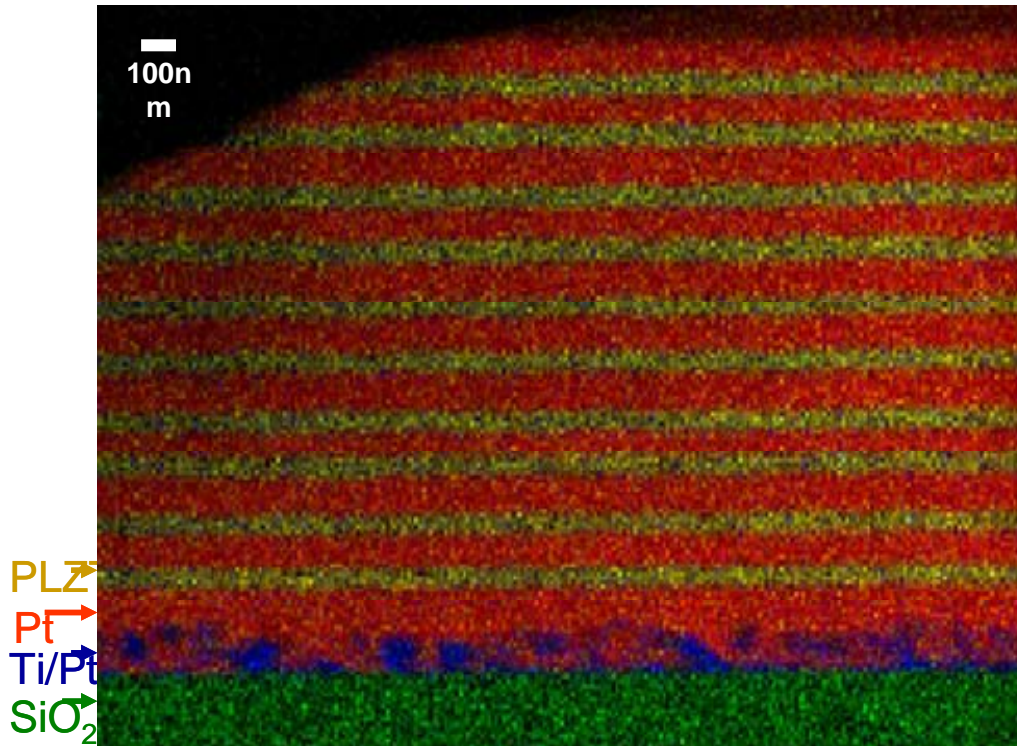
Zr-rich, Pb-deficient fluorite

stoichiometric perovskite



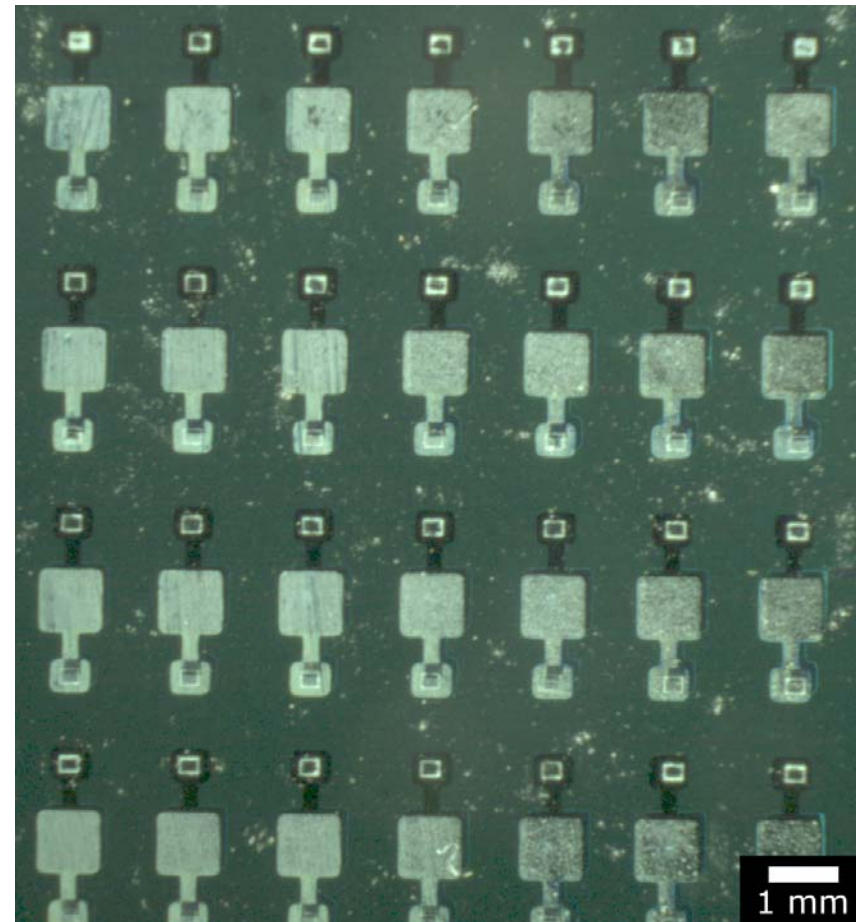
Ten Active Layer PLZT MLC Device, ~50nm

TEM Multivariate Spectral Image of Multilayer Cross-Section

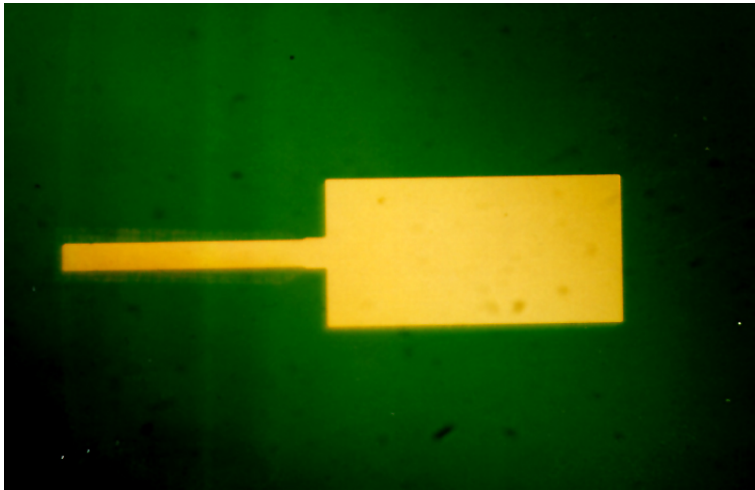


Enhanced Sensitivity per unit volume with thin multilayers

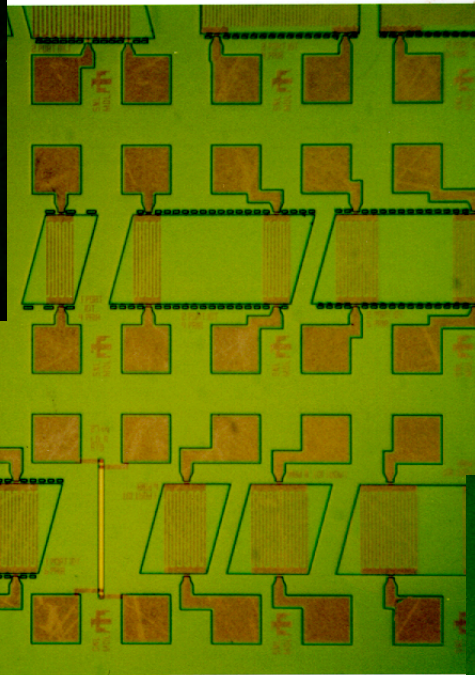
Batch Process Photolithographically Defined PLZT Ultrathin Film Devices



SNL Has Wide Ranging Efforts in MEMS Devices

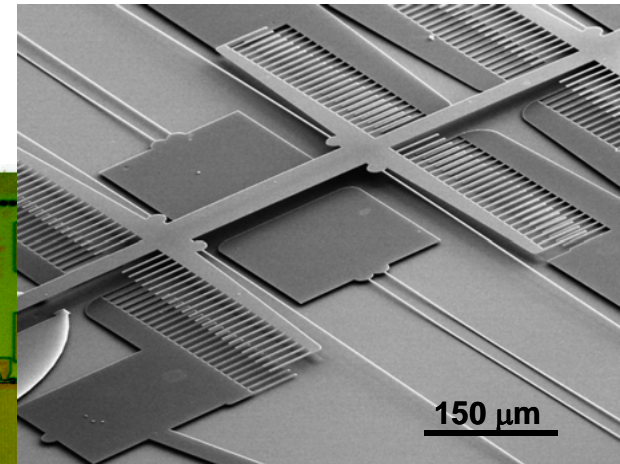


PZT – MEMs
Piezo Cantilever
Beam – Energy
Harvesting

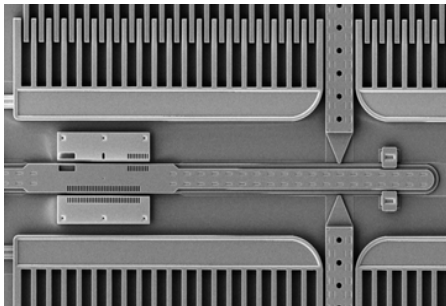
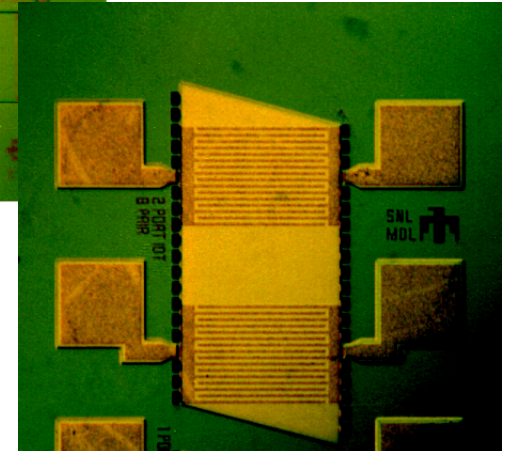


Bulk Acoustic Wave Modulators

Vapor phase lubricants
Extend slide life by 5 orders
Of Magnitude, D. Tanner



Alternate Hard Materials
ALD To Increase lifetime
SiC T. Friedman



SNL Patented Solution Chemistry Process Reproducible PZT Ceramics

SNL Chem-Prep Process

(Patent) Consists of:

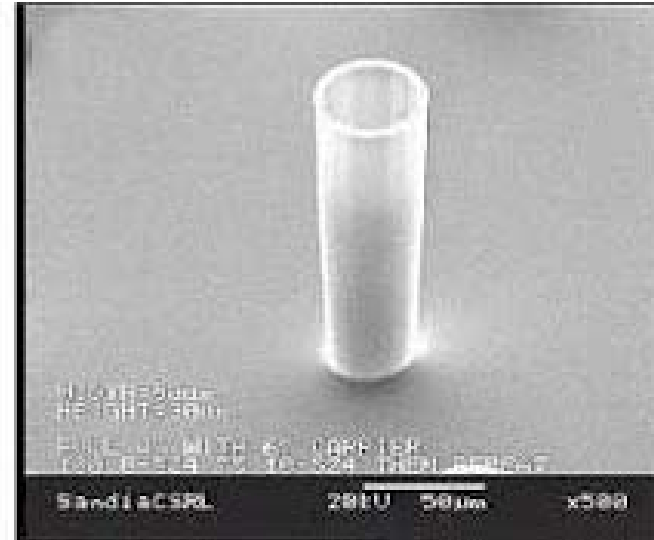
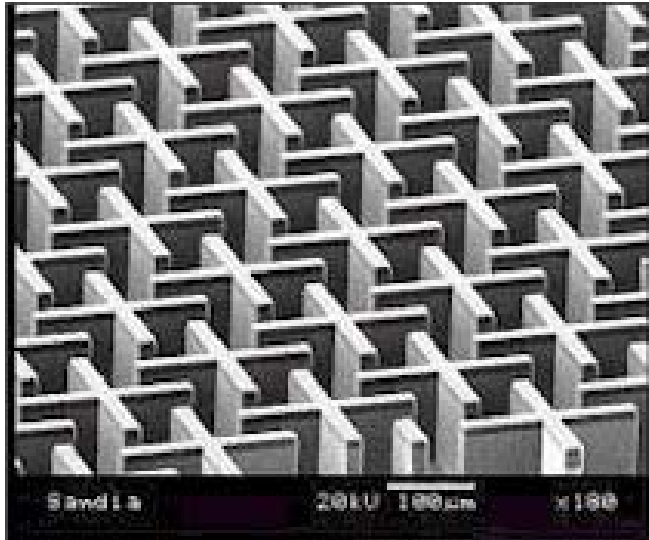
- 1) Synthesis of Pb Acetate
- 2) Dissolution of: A) Pb Acetate in Glacial Acetic Acid and B) Nb, Zr and Ti n-butoxides in Acetic Acid
- 3) Blending of the two solutions
- 4) Precipitation using Oxalic Acid / n-Propanol Solutions



Metal Solution Precipitated
With Oxalic Acid / n-Propanol

More than 100 batches of 1500 grams fabricated,
 ± 0.02 Mol% Ti, $\pm 0.5\%$ Remanent Polarization; $\pm 0.1\%$ Density

PZT Nanopowders to Enable Bosch Etched Micromold Patterns in Silicon for Sensors



Micromolding process: size of piezoelectric elements controlled by lithography that can achieve dimensions unachievable using dicing technology.

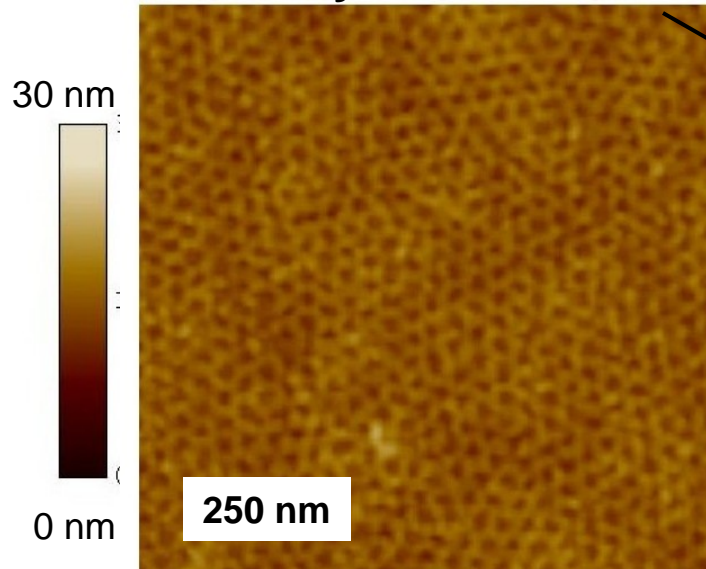
- 1) A glass mold of the pattern is prepared using standard lithographic and dry etching techniques.
- 2) Mold is filled with powder, pressed in standard press and sintered.
- 3) Excellent materials properties observed in large scale devices

Technical Challenge:

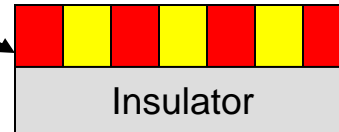
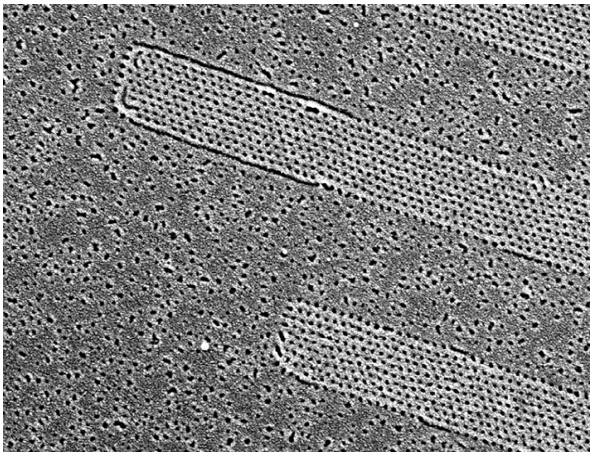
Nanocrystalline, mono-domain grain materials with ultraclean Grain boundaries.

Bilevel Patterning via Graphoepitaxy of Diblock Copolymers (UTA – NINE, J.Ekerdt)

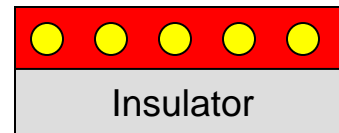
Cylinders



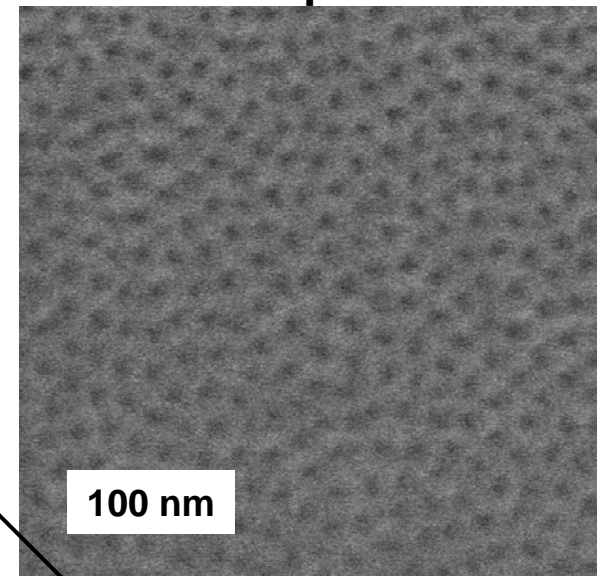
AFM image of cylindrical P(S-b-MMA) template on silicon dioxide after sputtered with gold for mechanical stability



PMMA
PS



Spheres



SEM image of spherical P(S-b-MMA) template

PMMA cylinders

70% styrene, 30% methyl methacrylate
20 nm diameter pores, $\sim 6 \times 10^{10} \text{ cm}^{-2}$

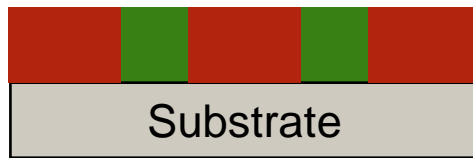
PMMA spheres in monolayer

83% styrene, 17% methyl methacrylate
12 nm diameter pores, $\sim 1.2 \times 10^{11} \text{ cm}^{-2}$

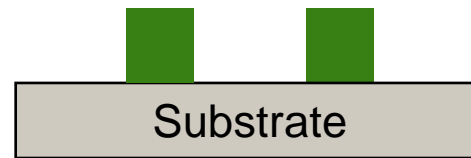
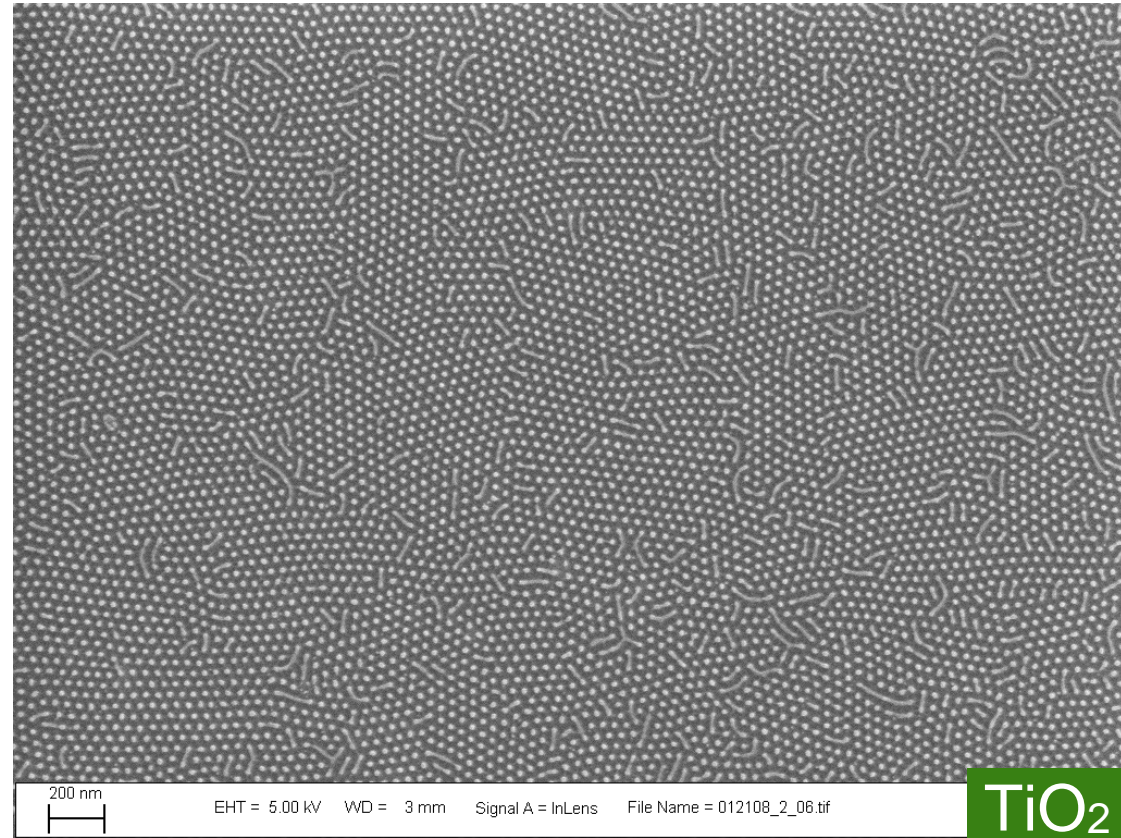
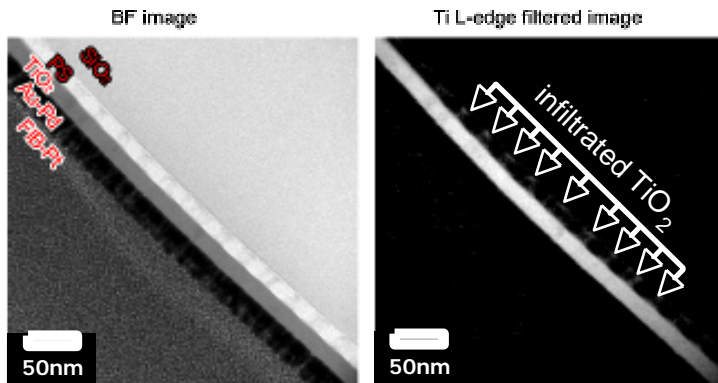
➤ If hexagonal, 31 nm
center-to-center

Soft Nanomaterials Development Leads to Patterned Hard Electronic Oxide Nanomaterials

UTA, SNL, UW NINE Collaboration (Paul Nealey UW and Erik Spoerke SNL Soft Matls)



Gel



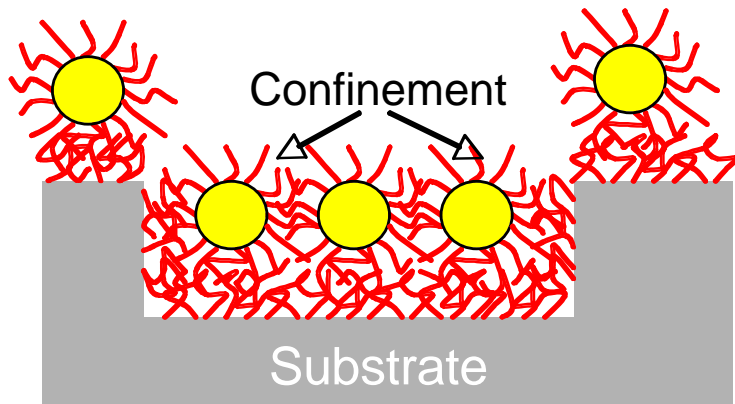
Remove PS

*Also demonstrated with
Ni, V, and Mn oxides in
nanofeatures; PZT in
microfeatures*

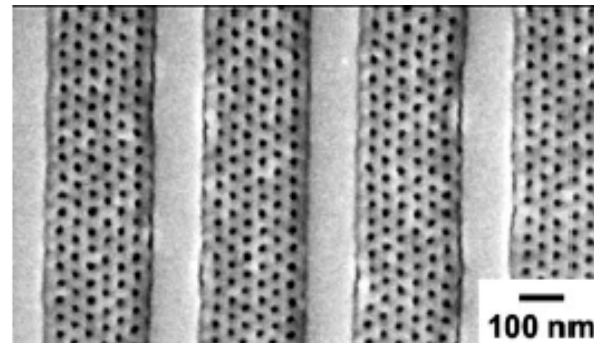
TiO_2 solution infiltrates 20nm columnar features
in nanopatterned PS (also shown for HfO_2)

Graphoepitaxy Demonstrated For SiO₂

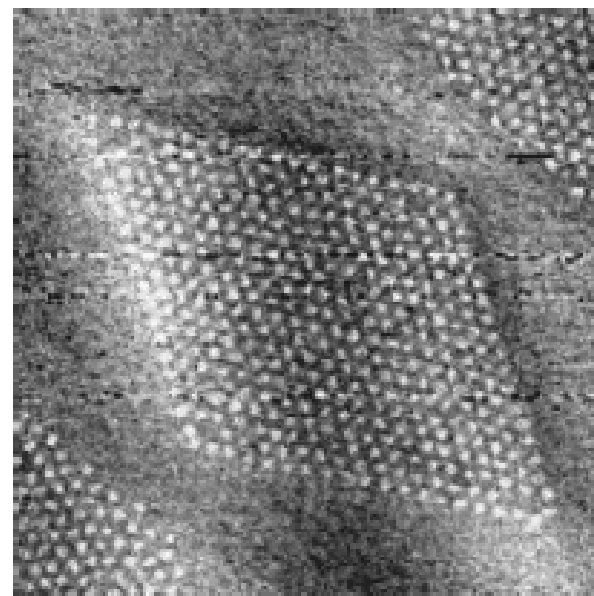
- Geometric confinement can lead to 'crystalline' single-domain state
- Demonstrated for Si / SiO₂ with cylindrical and spherical diblocks
- *Pre-defined pixel location*



R.A. Segalman, et al., Macromolecules, 36 4498-4506 (2003)



C. T. Black, et al., IEEE Trans. Nanotechnology 3 (5) 412-415 (2004)



Kimura, et al., MRS Symp. Proc. 901E, 0901-Ra05-05-Rb05-05.1 (2006)



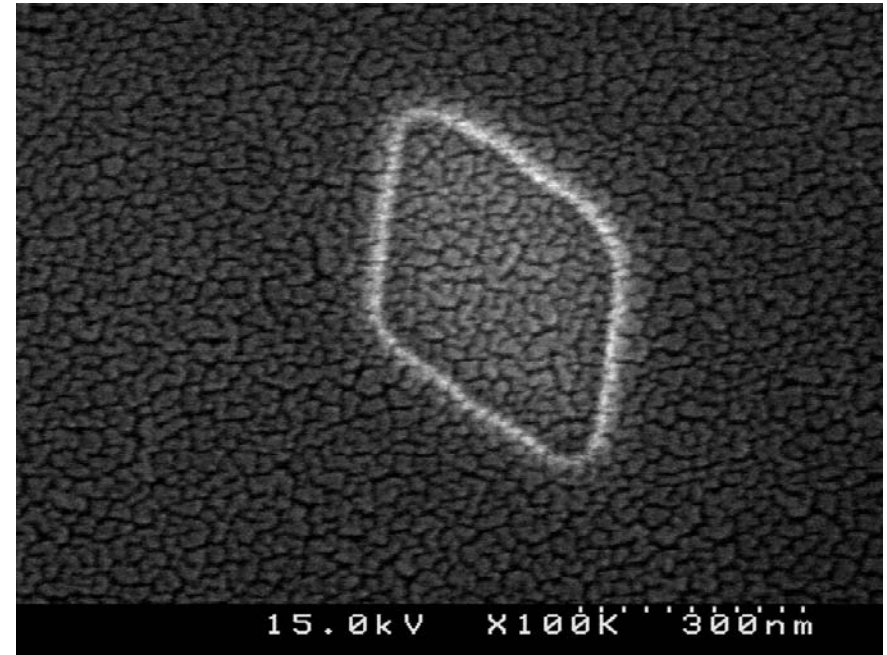
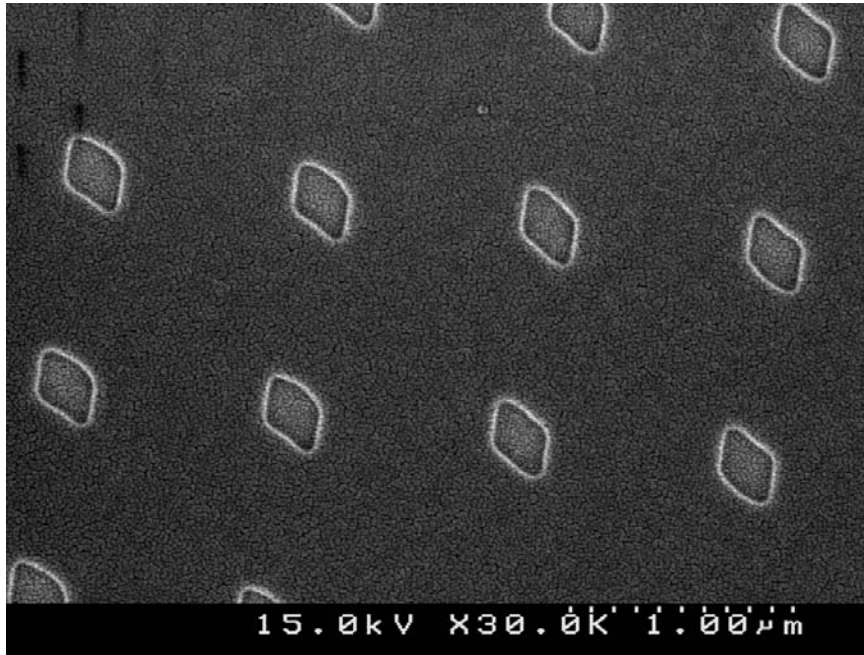
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NINE Collaborations Result in Game Changing Technological Advances

- Discussions with (SNL Experts) indicate US industry will Save Millions of Dollars with High Stability, Higher Sensitivity Extreme Environment Sensors
- Wide Range of Applications: Integrated Electronics Monitoring, Process Control, Well Drilling, etc.
- Control of Grain Size of Complex Oxide Materials and Grain Boundary Interfaces on the Nanoscale Essential for Extreme Environment Sensors and Actuators
- Mesh Industry Know How with University Fundamental Nano materials Expertise and SNL Nano-Micro Materials / Device Capabilities Can Result in Substantial Improvements for Extreme Environment Sensors

Transfer etch, SEM results using CINT EBL



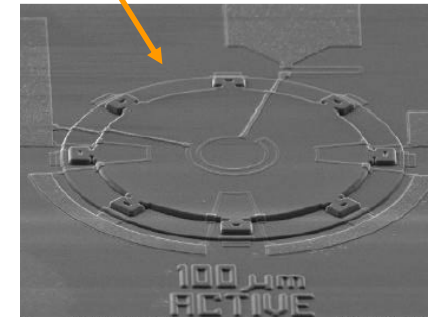
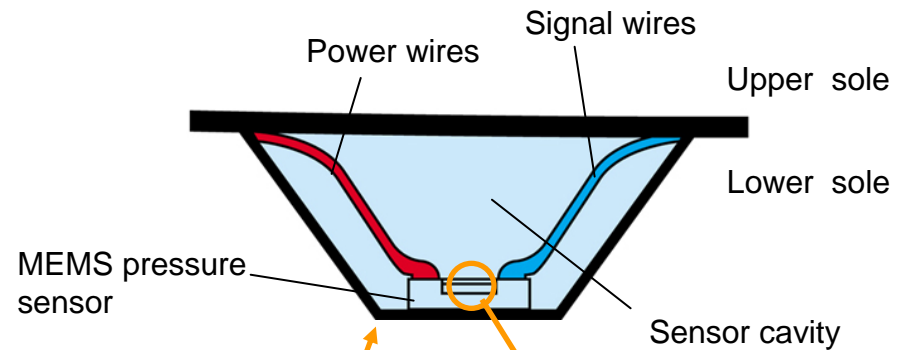
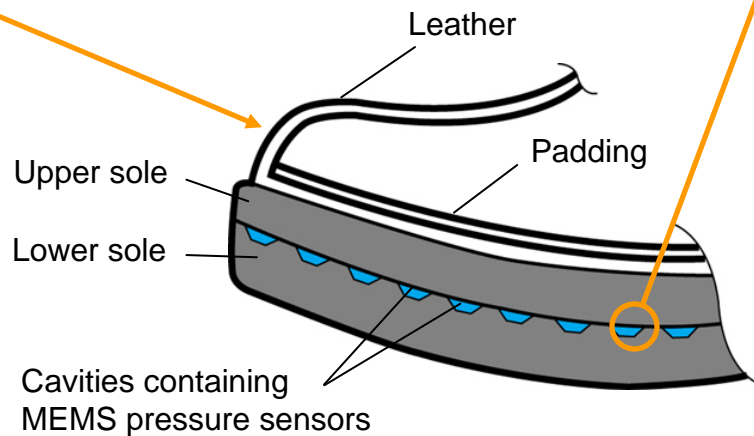
~0.3 micron parallelograms, transfer comes from 245 nm template



Sandia Developed Tools

- TPS Dewared Memory Tool
- Spectral Gamma Memory Tool
- CTDL Memory Tool
- Fluid Sampler
- Televiewer (Joint with Navy, USGS and Mount Sopris Instrument Co.)
- DWD POC and HT Drilling Tool
- PT Memory Drilling Tools (For Unsen Scientific Drilling Program - Tohoku University)
- Dewarless PT Well Monitoring Tools (For NETL and USGS)
- 300 C Analog PT Well Monitoring Tools

Transducer Packaging (1) ExoBoot: In-sole Pressure Profiler Concept (DARPA)

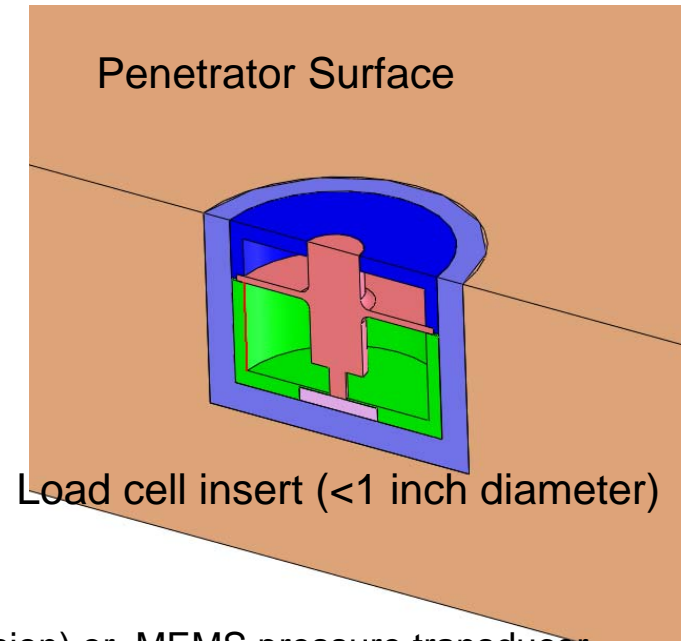
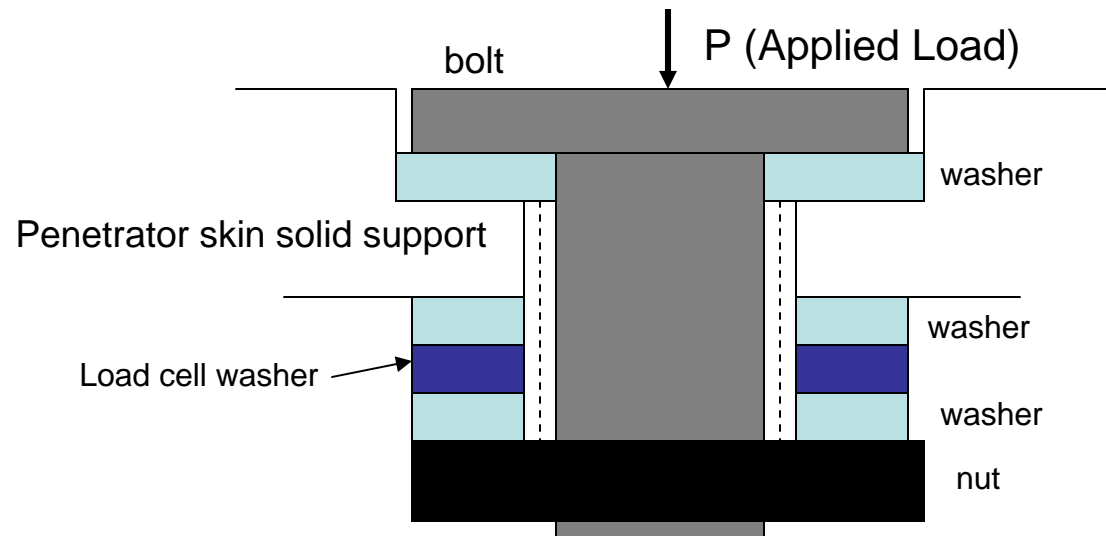


Deformable membrane
MEMS pressure sensor

MEMS Normal Stress Sensor for Monitoring Penetrator Loading

Vincent Luk (Department 5431) and Paul Galambos (Department 1769)

Threaded Load Cell Insert in Penetrator Skin.

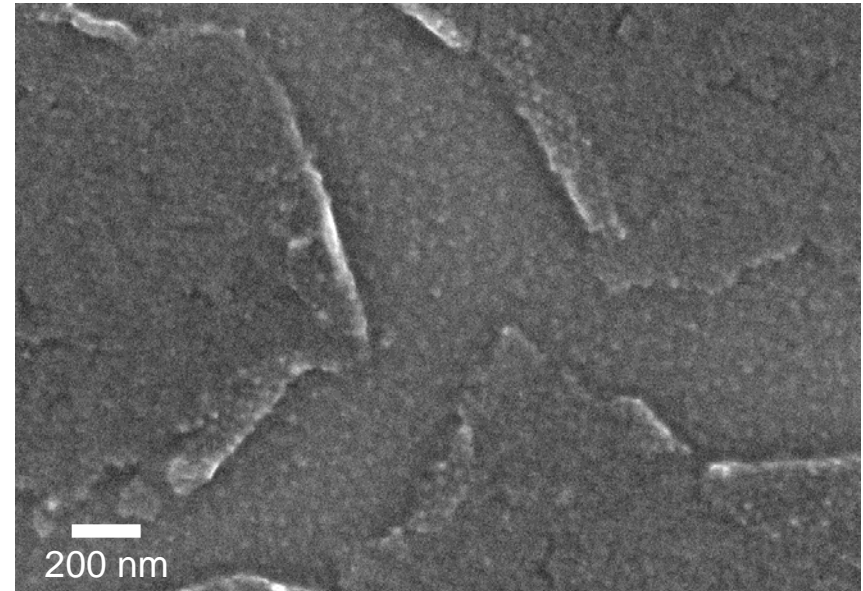
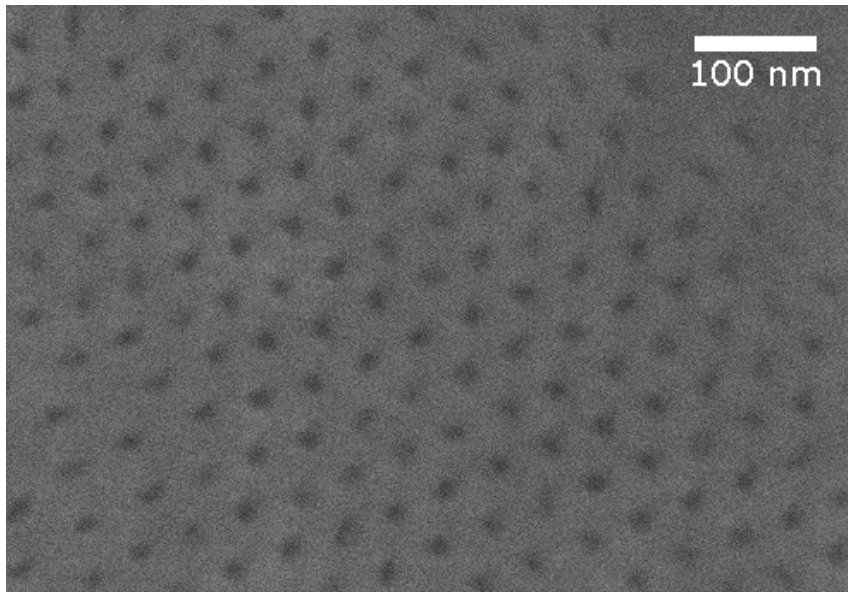


The load cell washer consists of a commercial load cell (COTS version) or MEMS pressure transducer array (high load MEMS version) and is the sensing element of the Penetrator surface load cell insert.

- COTS version bench test design under way – test this FY.
- MEMS design of pressure sensor array awaiting results of COTS test.
- MEMS pressure sensor array will provide higher load information in a smaller package than COTS load washer. Also, MEMS array will provide a load distribution providing more information about Penetrator surface load details (e.g. load angle, time history...)

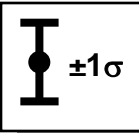
Nanopatterning: TiO_2 deposition

- Very little success since first attempt
- Problems appear to be due to removal of mask layer

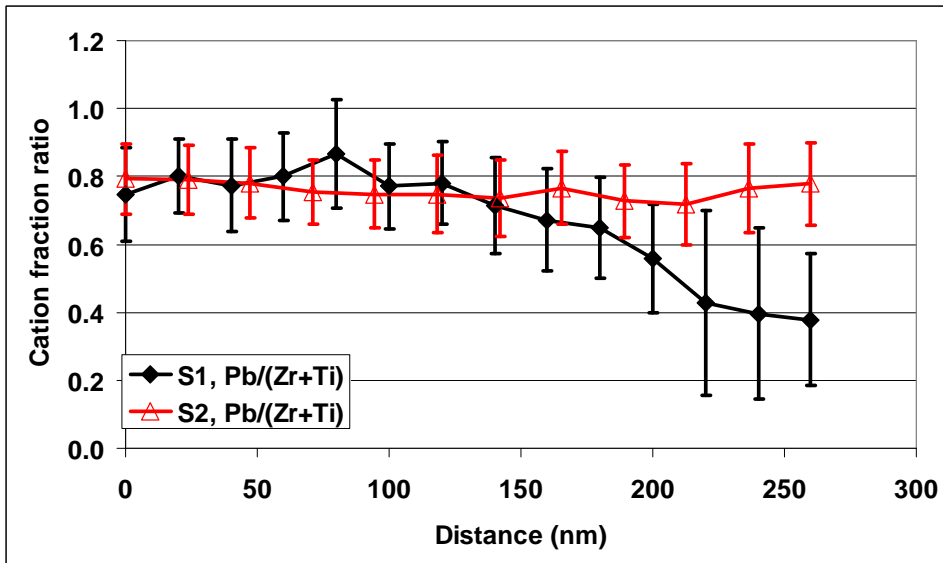


- Repeated exact procedure from first trial with longer 'soak' time before spinning; waiting for SEM

Spectral Image Derived Line Scans: Needed Analytical Tool



Traditional linescans



Extracted from SIs

